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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Application of:

Chia-Che Chuang

Group Art Unit: 2813

Serial No.: 10/656,585

Examiner: Hogans, David L.

Filed: Sept. 4, 2003

In Response to Office Action
Dated: Feb. 23, 2005

For: Apparatus and Method for Pre-Conditioning CMP
Polishing Pad

Attorney Docket No.: 67,200-1131

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date: Mar. 23, 2005


Kathy Dixon

RESPONSE TO OFFICE ACTION

Commissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

In response to an Office Action mailed Feb. 23, 2005 of a restriction requirement imposed by the Examiner, the Applicants hereby elect with traverse the prosecution of Group I, apparatus claims 1-8.